



PATENT  
Customer No. 22,852  
Attorney Docket No. 07553.0010

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )  
)  
Saito *et al.* ) Group Art Unit: 1763  
)  
Application No.: 09/686,370 ) Examiner: R. Kackar  
)  
Filed: October 12, 2000 )  
)  
For: Processing Apparatus for )  
Conservation of Processing Gases )  
(As Amended)

Commissioner for Patents  
Washington, DC 20231

Sir:

**AMENDMENT**

In reply to the Office Action dated October 16, 2002, please amend the application as follows:

**IN THE CLAIMS:**

Please add new claims 16-23.

Please amend claims 1 and 15 as follows:

1. (Three Times Amended) A processing apparatus comprising:

C1 a gas supply mechanism that supplies a processing gas into a processing chamber via a plurality of gas supply holes including a plurality of primary gas supply holes and a plurality of circulating gas supply holes,

an evacuating mechanism that evacuates the processing gas from said processing chamber, and

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